

ABSTRACT

The method for generating radicals comprises:
feeding F₂ gas or a mixed gas of F₂ gas and an inert gas
into a chamber of which the inside is provided with a carbon
5 material,
supplying a carbon atom from the carbon material by
applying a target bias voltage to the carbon material, and
thereby
generating high density radicals,
10 wherein the ratio of CF₃ radical, CF₂ radical and CF
radical is arbitrarily regulated by controlling the target bias
voltage applied to the carbon material while measuring the
infrared absorption spectrum of radicals generated inside the
chamber.